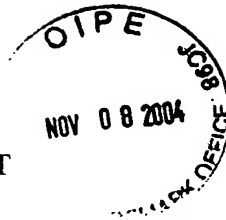


DOCKET NO: 247903US90CONT



IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF :
TETSUO TANIGUCHI : EXAMINER: NGUYEN, H.
SERIAL NO: 10/773,293 :
FILED: FEBRUARY 9, 2004 : GROUP ART UNIT: 2851
FOR: EXPOSURE METHOD AND :
LITHOGRAPHY SYSTEM, EXPOSURE
APPARATUS AND METHOD OF
MAKING THE APPARATUS, AND
METHOD OF MANUFACTURING
DEVICE

PRELIMINARY AMENDMENT
AND
RESPONSE TO RESTRICTION REQUIREMENT

COMMISSIONER FOR PATENTS
ALEXANDRIA, VIRGINIA 22313

SIR:

Responsive to the Restriction Requirement stated in the Office Action dated October 8, 2004 and prior to an examination on the merits, please amend the above-identified patent application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks begin on page 9 of this paper.